## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	) Previous Examiner: K. Sagar
Takako YAMAGUCHI et al.	: ) Previous Group Art Unit: 1756
Application No.: Divisional of Application No. 09/781,331, filed February 13, 2001	: ) :
Filed: July 31, 2003	) : ) July 31, 2003
For: PATTERN-FORMING APPARATUS USING A PHOTOMASK (As Amended)	, , ,

## Mail Stop Patent Application

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## PRELIMINARY AMENDMENT AND LETTER SUBMITTING SUBSTITUTE SPECIFICATION

Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

## IN THE TITLE

Please amend the title as shown in the substitute specification.